

Use of a 1*H*-Benzoimidazole Derivative as an *n*-Type Dopant and To Enable Air-Stable Solution-Processed *n*-Channel Organic Thin-Film Transistors

Peng Wei,[†] Joon Hak Oh,[†] Guifang Dong,^{†,‡} and Zhenan Bao^{*,†}

Department of Chemical Engineering, Stanford University, Stanford, California 94305, and Department of Chemistry, Tsinghua University, Beijing 100084, P. R. China

Received April 15, 2010; E-mail: zbao@stanford.edu

The design of circuits utilizing organic complementary metal oxide semiconductor (CMOS) architecture requires the development of both *p*-channel and *n*-channel semiconductors with high performance and air-stability. Compared to highly developed *p*-channel organic semiconductors, the availability of high-performance, air-stable *n*-channel materials, in particular with solution processability, remains considerably limited.¹ This is attributed to the vulnerability of electrons to trapping by ambient oxidants, such as O₂ and H₂O.² These ambient traps result in significant decreases of the density of mobile electrons in *n*-channel organic thin-film transistors (OTFTs) and, thus, poor air-stability. The difficulties encountered in the development of new, air-stable *n*-channel semiconductors prompted us to seek a new approach to increase the density of mobile electrons to compensate for the trapped electrons under ambient conditions. We hypothesized that controlled *n*-type doping might fulfill this requirement. Previous attempts at intentional doping have increased film conductivities as a result of increased charge carrier density,³ with the approach resulting in highly efficient organic light-emitting diodes (OLEDs)⁴ and organic photovoltaics (OPVs).⁵ However, the design of *n*-type (vs *p*-type) dopants is considerably challenging owing to the requirement of high-lying dopant highest occupied molecular orbital (HOMO) levels, making *n*-type dopants unstable against O₂.^{3c} A promising strategy involves the formation of the active dopant species through thermal activation or photoactivation, allowing the active *n*-type dopants to transfer electrons to the host matrix and form stable cations.^{3b,d} However, most previously reported dopants were processed by vacuum deposition and required high conversion temperatures. These dopants were thus incompatible with solution-processed materials and demonstrated weak doping effects (i.e., insufficient to render the device air-stable). Therefore, it is essential to design new *n*-type dopants for solution-processed *n*-channel OTFTs.

1,3-Dimethyl-2-phenyl-2,3-dihydro-1*H*-benzoimidazole (DMBI) derivatives have been reported as effective reagents for reductive transformations of organic compounds.⁶ These materials are also known to promote hydrogen- and/or electron-transfer reactions via radical formation.⁷ Thus, these solution-processable moieties present an ideal class of *n*-type dopants, as they readily form neutral radicals and H radical.⁶ In this Communication, we report the use of (4-(1,3-dimethyl-2,3-dihydro-1*H*-benzoimidazol-2-yl)phenyl)dimethylamine (N-DMBI, Figure 1a) as an *n*-type dopant and demonstrate improved air-stability of N-DMBI-doped *n*-channel OTFTs by solution processing.

To characterize the doping effect of N-DMBI, film conductivities of a well-known solution-processable *n*-channel semiconductor, [6,6]-phenyl C₆₁ butyric acid methyl ester (PCBM),⁸ were explored. N-DMBI and PCBM were mixed at varying ratios and spin-coated from chlorobenzene solutions to form thin films. The dopants were activated by heating the films at 80 °C overnight in a N₂-filled

glovebox. The conductivities of N-DMBI-doped films increased considerably (Figure 2a), with the highest conductivity (ca. 1.9 × 10⁻³ S/cm) being more than 4 orders of magnitude higher than that of undoped PCBM film (8.1 × 10⁻⁸ S/cm). These values approach the highest reported conductivities for *n*-type doped organic semiconductors,^{3b,c,9} indicating the strong doping ability of N-DMBI. The film conductivities increased superlinearly with regard to the doping concentration of N-DMBI. This can be attributed to the tendency of N-DMBI for aggregation (Figure 2a, inset) and the localization of the donated electrons around dopant molecules in the films.¹⁰

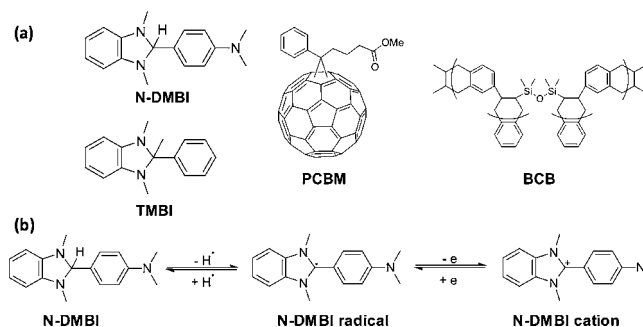


Figure 1. (a) Chemical structures of the materials. (b) Proposed mechanism of hydrogen and electron transfer for *n*-type doping.

PCBM transistors were fabricated with a bottom-gate, top-contact configuration. A thin (20 nm), thermally cross-linked divinyltetramethyldisiloxane bis(benzocyclobutene) (BCB) layer was used to eliminate electron traps that can arise from surface hydroxyl groups on SiO₂.^{1d,2c,8b} The use of BCB increased the electron mobility of PCBM transistors by 1 order of magnitude (1.24 × 10⁻¹ cm²/(V·s), in N₂) as compared to that of transistors fabricated directly on SiO₂ dielectric (1.68 × 10⁻² cm²/(V·s), in N₂).

The performance of N-DMBI-doped PCBM OTFTs in a N₂-filled glovebox is shown in Figure 2b. The threshold voltage (*V*_t) of OTFTs is typically employed to evaluate the minimum gate bias (*V*_{gs}) required to fill trap states so that mobile charges start to move under drain–source bias. From the transfer characteristics of the doped devices, *V*_t systematically negatively shifted with increasing doping concentration. This indicates that a lower gate voltage is needed to turn on the transistors after *n*-type doping. Hysteresis was not observed with all doping concentrations (Figure S3, Supporting Information (SI)). At low doping concentrations (0.5 and 2 wt%), the mobilities remained around 0.1 cm²/(V·s). At high doping concentrations (5 and 10 wt%), the off-current increased by more than 5 orders of magnitude compared to that of the undoped PCBM device. However, there was no significant difference in the on-current at the same *V*_{gs}.

The lowest unoccupied molecular orbital (LUMO) level of PCBM is around -3.80 eV,¹¹ which is much higher than the HOMO of N-DMBI (-4.67 eV).⁶ This means that electron transfer cannot

[†] Stanford University.

[‡] Tsinghua University.

spontaneously occur between N-DMBI and PCBM molecules. However, Gaussian 03¹² calculations reveal the singly occupied molecular orbital (SOMO) level of the neutral radical of N-DMBI after hydrogen removal to be -2.36 eV. Thus, the neutral radical species allows for electron transfer from the N-DMBI neutral radical to the PCBM. Besides, a stable n -type doping effect could be obtained by stabilizing the N-DMBI cation by the adjacent electron-rich phenyl ring and two nitrogen atoms, making the electron-transfer process irreversible. Therefore, the highly energetic radicals are presumed to be responsible for the strong doping effect of N-DMBI. Moreover, the vis-NIR absorption spectra of the doped film also indicated electron transfer from N-DMBI to PCBM (Figure S4, SI).¹³ To further elucidate the nature of the mechanism, 1,2,3-trimethyl-2-phenyl-2,3-dihydro-1H-benzoimidazole (TMBI) was used as the dopant, wherein the imidazole core hydrogen was replaced with a methyl group (Figure 1a). No obvious n -type doping effect was observed in TMBI-doped transistors (i.e., negative V_t shift and decrease of on-off ratio) (Table S1, SI). This is consistent with our hypothesis on the doping mechanism.

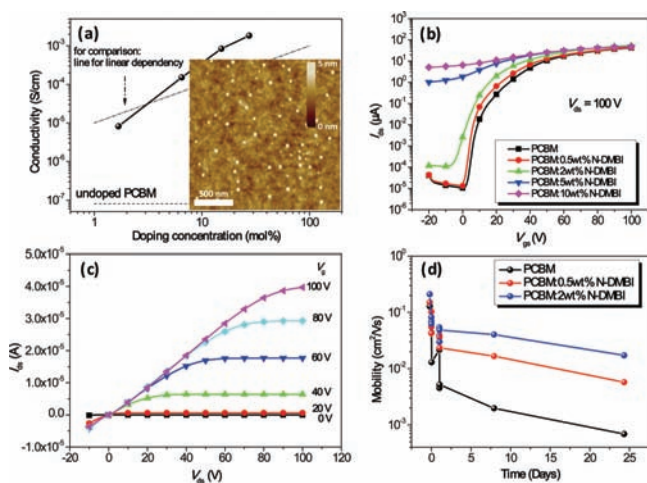


Figure 2. (a) Conductivities of undoped and N-DMBI-doped PCBM films at varying doping concentrations. Inset: AFM image of 2 wt% N-DMBI-doped PCBM film. (b) Transfer characteristics of N-DMBI-doped PCBM OTFTs at varying doping concentrations in a glovebox. (c) Output characteristics of 0.5 wt% N-DMBI-doped PCBM OTFTs in a glovebox. (d) Changes of field-effect mobilities in air as a function of time for undoped and 0.5 and 2 wt % N-DMBI-doped PCBM OTFTs.

The long-term air-stability of undoped and 0.5 and 2 wt% N-DMBI-doped PCBM transistors was monitored by measuring the performance as a function of time (Figure 2d). For undoped OTFT, the performance degraded rapidly, although the SiO₂ surface was passivated by the hydroxyl-free BCB layer. The introduction of N-DMBI dopants improved the air-stability of PCBM OTFTs. Significantly, the mobility of 2 wt% N-DMBI-doped PCBM OTFTs remained higher than 10^{-2} cm²/(V·s), even after 20 days. We attribute this improved stability to the compensatory effect of the dopant on the O₂ electron traps. To our knowledge, this is the first successful demonstration of an n -type dopant enabling air-stability in n -channel OTFTs, although there were reports of n -type doping on n -channel OTFTs for increasing conductivity or crystallization.^{9,14} Preliminary results also indicate that this methodology can enable air-stability in vapor-processed N,N' -ditridecyl perylene diimide OTFTs. These results indicate n -type doping is a promising method to incorporate existing air-sensitive n -channel semiconductors for practical applications.

In summary, we have developed a new, solution-processable n -type dopant, N-DMBI. PCBM can be effectively doped with N-DMBI by solution processing, and the conductivities of doped films are significantly increased. We demonstrate that N-DMBI neutral radicals are

the key species enabling n -type doping. Furthermore, we utilized this dopant to enable and improve the air-stability of n -channel OTFTs by compensating for the ambiently trapped electron charge carriers. Our successful demonstration of n -type doping opens up new opportunities for the development of air-stable n -channel semiconductors. We also envision potential applications to solution-processed OLEDs and OPVs. Systematic studies on doping mechanisms and the development of additional DMBI derivatives for both solution processing and vacuum deposition are underway.

Acknowledgment. We are grateful of AFOSR (Grant No. FA9950-09-1-0256) for support of this work.

Supporting Information Available: Details of experimental procedures, discussion on the doping mechanism, complete ref 12, vis-NIR absorption spectra of the thin films of undoped and 10 wt% N-DMBI-doped PCBM, and OTFT data. This material is available free of charge via the Internet at <http://pubs.acs.org>.

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JA103173M